IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450 Inventor(s):

Re:

Songlin Xu, Thorsten B. Lill, Yeajer Arthur Chen, Mohit Jain, Nicolas Gani, Shing-Li Sung, Jitske

K.Trevor-Kretz, Meihua Shen, Farid Abooameri

Title: PROCESS FOR ETCHING POLYSILICON GATES WITH GOOD MASK SELECTIVITY.

CRITICAL DIMENSION CONTROL, AND CLEANLINESS

Transmitted herewith is the patent application identified above, including:

- X Specification, claims and abstract, totaling 21 pages.
- X Drawings totaling 7 pages, X Formal Informal.
- х Executed Declaration and Power of Attorney.
- х Assignment of the invention to Applied Materials, Inc.
- X Assignment Recordation Cover Sheet
- X Information Disclosure Statement and Form 1449 along with copies 6 references recited therein

Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	20	-20=		X\$18.00	\$000.00
Independent Claims	3	-3=		X\$84.00	\$000.00
Basic Filing Fee \$750.00					\$750.00
TOTAL FEES					\$750.00

- X The Commissioner is hereby authorized to charge \$ 750.00 to Deposit Account No. 50-1074.
- Х The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.
- XXPlease address all future correspondence to:

PATENT COUNSEL APPLIED MATERIALS, INC. Legal Affairs Department

P.O. BOX 450A

Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231.

EV341110525 US Express Mail Receipt No.

W. Mulcahy Registration No. 25

Respectfully submitted,